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Novel in-situ lamella fabrication technique for in-situ TEM

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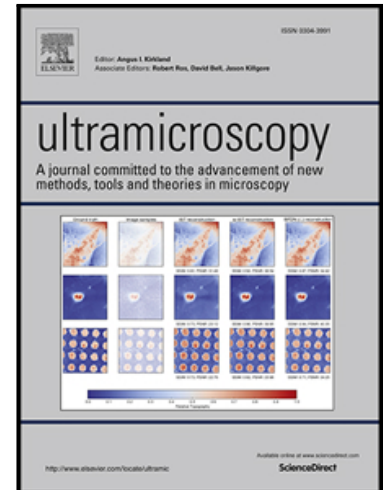
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Highlights

- A novel in-situ lamella fabrication technique for in-situ TEM annealing is proposed
- Use of rotating microgrippers and unique adhesive for lamella thinning and mounting
- Removes the risk of Pt re-deposition and ion beam damage to the MEMS device

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